Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	568534	(mem$1 micromechanical microelectromechanical micro adj mechanical micro adj electromechanical) (MicroOptoElectroMechanical Micro adj (Opto adj Electro OptoElectro) adj Mechanical MOEM$6 micromachin$3 microstructur$3 microdevic$3 micro)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 12:12
L3	909806	(dielectric insulat$4 sin sio silicon adj (nitride oxide)) near (layer film material)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:36
L4	1085164	(silicon polysilicon polycrystalline conduct$4 metal$4) near (layer film material)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:38
L5	2380572	thick$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:38
L6	1	10/790339	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:39
L7	536624	fifth 1/5	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:41
L8	1525879	thin	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:42
L9	100633	5 near3 3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:42
L10	82524	5 near3 4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:45
L11	4905397	mechanical$4 property characteristic	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:47

L12	115	10 near5 8 near5 11	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:48
L13	0	12 same 1	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:47
L14	2632	4 near5 8 near5 11	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:49
L15	35	14 with 1	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:52
L16	2	15.clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:49
L17	2982229	enough sufficient$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:52
L18	2	15 with 17	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:52
L19	69	14 with 17	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:53
L20	2	19 same 1	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:53
L21	6	19 and 1	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 10:53

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L22	15888	1.clm.	US-PGPUB	OR	ON	2006/01/05 12:08
L23	50806	3.clm.	US-PGPUB	OR	ON	2006/01/05 12:08
L24	60433	4.clm.	US-PGPUB	OR	ON	2006/01/05 12:09
L25	86508	5.clm.	US-PGPUB	OR	ON	2006/01/05 12:09
L26	21099	7.clm.	US-PGPUB	OR	ON	2006/01/05 12:14
L27	38	22 and 23 and 24 and 25 and 26	US-PGPUB	OR	ON	2006/01/05 12:09
L28	638976	(mem$1 micromechanical microelectromechanical micro adj mechanical micro adj electromechanical) (MicroOptoElectroMechanical Micro adj (Opto adj Electro OptoElectro) adj Mechanical MOEM$6 micromachin$3 microstructur$3 microdevic$3 micro) cantilever	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/01/05 12:12
L29	28988	8.clm.	US-PGPUB	OR	ON	2006/01/05 12:14
L30	21099	7.clm.	US-PGPUB	OR	ON	2006/01/05 12:14
L31	17839	28.clm.	US-PGPUB	OR	ON	2006/01/05 12:15
L32	68718	3 and 4 and 5	US-PGPUB	OR	ON	2006/01/05 12:15
L33	2887	32 and 31	US-PGPUB	OR	ON	2006/01/05 12:15
L34	93	33 and 30	US-PGPUB	OR	ON	2006/01/05 12:16
L35	10356	23 and 24 and 25	US-PGPUB	OR	ON	2006/01/05 12:16
L36	428	35 and 31	US-PGPUB	OR	ON	2006/01/05 12:16
L37	39	36 and 30	US-PGPUB	OR	ON	2006/01/05 12:18
L38	39	(US-20040164423-$ or US-20050219017-$ or US-20050051515-$ or US-20050037531-$ or US-20050024161-$ or US-20040235205-$ or US-20040126921-$ or US-20040115843-$ or US-20040092045-$ or US-20040072386-$ or US-20040012460-$ or US-20030189788-$ or US-20030148550-$ or US-20030019833-$ or US-20030011786-$ or US-20020190207-$ or US-20020188417-$ or US-20020182760-$ or US-20020180986-$ or US-20020180985-$ or US-20020180961-$ or US-20020179867-$ or US-20020179864-$ or US-20020168831-$ or US-20020107660-$ or US-20020107650-$).did. or (US-20020106848-$ or US-20020103564-$ or US-20020102749-$ or US-20020102352-$ or US-20020097406-$ or US-20020093648-$ or US-20020033927-$ or US-20020000583-$ or US-20010043545-$ or US-20010021166-$ or US-20010021159-$ or US-20010019532-$ or US-20010010676-$).did.	US-PGPUB	OR	ON	2006/01/05 12:18
L39	39	38 and 30	US-PGPUB	OR	ON	2006/01/05 12:29
L40	28988	8.clm.	US-PGPUB	OR	ON	2006/01/05 12:29
L41	2946	much.clm.	US-PGPUB	OR	ON	2006/01/05 12:30
L42	140	36 and 40	US-PGPUB	OR	ON	2006/01/05 12:30
L43	0	42 and 41	US-PGPUB	OR	ON	2006/01/05 12:30

L44	2	36 and 41	US-PGPUB	OR	ON	2006/01/05 12:31
L45	3693	thinner.clm.	US-PGPUB	OR	ON	2006/01/05 12:31
L46	7	36 and 45	US-PGPUB	OR	ON	2006/01/05 12:34
L47	51560	smaller.clm.	US-PGPUB	OR	ON	2006/01/05 12:34
L48	34	36 and 47	US-PGPUB	OR	ON	2006/01/05 12:34
L49	31	48 not 39	US-PGPUB	OR	ON	2006/01/05 12:35
L50	31	(US-20060001508-$ or US-20050264617-$ or US-20050236055-$ or US-20050226778-$ or US-20050221529-$ or US-20050214160-$ or US-20050212540-$ or US-20050200985-$ or US-20050156320-$ or US-20050095722-$ or US-20050046002-$ or US-20040258355-$ or US-20040232519-$ or US-20040113276-$ or US-20040082173-$ or US-20040075050-$ or US-20040061176-$ or US-20040001264-$ or US-20030211666-$ or US-20030205731-$ or US-20030198037-$ or US-20030197457-$ or US-20030183008-$ or US-20020195932-$ or US-20020182631-$ or US-20020173091-$).did. or (US-20020125582-$ or US-20020102857-$ or US-20020071169-$ or US-20020024351-$ or US-20010038148-$).did.	US-PGPUB	OR	ON	2006/01/05 12:34
L51	31	50 and 47	US-PGPUB	OR	ON	2006/01/05 12:35
L52	3633	25 with 47	US-PGPUB	OR	ON	2006/01/05 12:35
L53	13	51 and 52	US-PGPUB	OR	ON	2006/01/05 12:35

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